# SIMULATION OF 10 NM DOUBLE GATE MOSFET USING VISUAL TCAD TOOL

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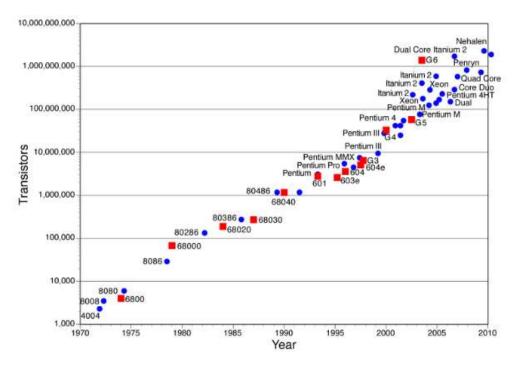
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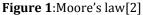
**Abstract** -Evolution of Silicon technology has revolutionized the semiconductor industry. The characteristics of MOSFET has been subsequently degraded by continuous scaling. A Double gate MOSFET is proposed to overcome the limitations of conventional MOSFETs. Due to continuous scaling MOSFET's performance are highly effected by short channel effects. These short channel effects (SCE) are responsible for reduction of gate coupling to the channel. In order to improve gate coupling, a double gate MOSFET is being proposed in this work and its comparative analysis is done using Cogenda TCAD genius simulator. In this work our main focus is to perform simulation of 10 nm Double gate MOSFET on Visual TCAD software and to extract the transconductance, DIBL, Ion –Ioff ratio and other important parameters of the device.

Key words: Short channel effects (SCE), Drain induced barrier limiting (DIBL), Visual TCAD, Double gate MOSFET.

# **1. INTRODUCTION**

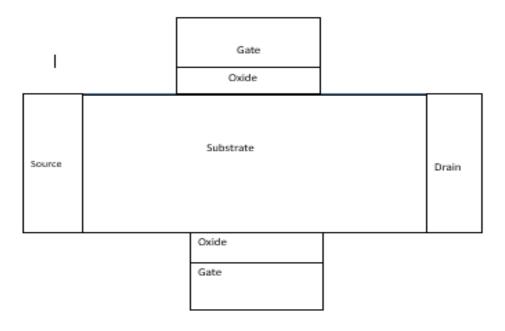
Since three decades or more MOSFETS have been continually scaled down from micrometer to nanometer range and from nanometer to sub nanometer range to validate Moore's law as shown in Figure 1. According to Moore the count of transistors are doubled in every eighteen months which of course enhances the processing power of device almost twice in every eighteen months [1]. Today due to scaling we are able to put together billions of transistors on single chip. However reducing the gate length below certain limits results in loosing of control of gate over channel because of presence of SCEs [2].





Various conventional techniques has been observed by researchers for the reduction of these SCE these include, reducing gate oxide thickness and using high k dielectric gate oxide like HfO<sub>2</sub>. But all these have limitations reducing oxide thickness increases leakage current which leads to increase in static power dissipation. Below 20 nm with reduced oxide thickness tunneling current is more common which increases power dissipation. Using HfO<sub>2</sub> increases compatibility issues with existing silicon technology. In order to hold Moore's law valid till today non-classical techniques are being used i.e. Using

multi gate MOSFET, Finfet, Gate all-around MOSFETs etc. These multi gate MOSFETS has been used to overcome the limitations of single gate MOSFETs. Double gate Mosfets reduces leakage current subthreshold slope and DIBL parameters, therefore having clear dominance over single gate MOSFET. The Double gate MOSFET having two gate terminals along with two gate oxides which lies above and below the substrate as shown in Figure 2.



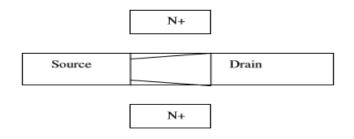
**Fig 2:** Double gate MOSFET structure.

Due to presence of two gates the electrostatic control of gate over channel is increased. Which results in increase of drain and is almost twice when compared to single gate Mosfet.Because of presence of two gates, between source and drain electric field lines are omitted. The main focus of Double gate MOSFET is to gain maximum control over the silicon channel very effectively by proper selection of channel width and by applying proper gate voltage. It has been observed that increasing the number of gates provides better control over channel and their by improving device performance [3-6].

#### 1.1 Double Gate Mosfet Operation

Double gate MOSFET having mostly undoped conducting channel with gate terminals surrounding this conducting channel in order to make sure that each part of channel is very close to the gate terminal [7]. When the voltage is applied at the gate terminals two conducting channels are created which are very close to the Si-SiO<sub>2</sub> Interface. The electric field is controlled by applied gate voltage their by defining the amount of current passing through the channel. Based upon the application of gate voltage we have two types of Double gate MOSFETs

**Symmetrical DG MOSFETs:** A DG is said to be symmetrical when at both gates same input voltage is applied and when both are of same work function as shown in Figure 3. In on state, at same gate voltage two Conducting channels are created above and below the Si substrate, Conduction occurs simultaneously in both these channels [8].





**Asymmetrical DG MOSFET:** A DG is said to be asymmetrical when different voltages are applied at gate with same work function or same voltages are applied at gate with different work functions as shown in Figure 4.In this only single channel is created and at a very high operational voltage another inversion channel may be created. Switching is obtained when different gate voltages are applied at gate terminals [9].

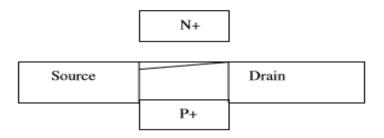


Figure 4: Asymmetrical DG MOSFET [3]

# **1.2 Short channel Effects:**

With devices scaled below sub nanometer range, the source an drain terminals are so close that their presence decreases the control of gate over channel and hence reduces current flow in the channel. Therefore the undesirable effects called short channel effects are introduced in the device.

**DIBL:** For short channel devices DIBL effect occurs when depletion region of S/D starts interacting which results in lowering of potential barrier. A little increase in drain voltage further reduces this barrier. Therefore an additional carriers are injected into the channel region but this increase in carrier concentration is function of drain voltage and not of gate voltage [10].

DIBL=  $\Delta V th / \Delta V ds$ .....i

**Subthreshold Slope:** When Vgs is lower than Vth it is believed that transistor should be completely in off state, but actually a small and weak inversion channel exits due to which a small current flows between source and drain and transistor is said to be operating in subthreshold region. The minority concentration is very less in weak inversion region. The scalability limit of device is determined by this subthreshold slope parameter [11-14].

SS=  $(d(\log I_{ds})/dV_{gs})^{-1}$ .....ii

#### **1.3 COGENDA TCAD TOOL:**

Cogenda TCAD tool is a GUI for device simulation. Cogenda tool is designed in order to suit with every user and every student, and its main focus on the ease of use. TCAD tool is very easy to use, command line or coding are also used. Beginners need a very less time just a few minutes to get started. At the same time doesn't sacrifices the power of Genius simulator. Various physical models and various options can be accessed with this TCAD tool. This TCAD tool is capable of doing 2D as well as 3D device simulations.

For our simulation purposes we have used Cogenda TCAD tool, which is basically a device simulator tool. In this tool we can design any structure and can visualize, study and predict its behavior.in this tool we can perform steady state analysis, AC analysis, circuit analysis etc.in this tool we can simulate device in order to obtain its electrical characteristics like current, voltage, capacitance and carrier density etc.it is a useful tool because of reduced design cost, with improved design productivity. Its important components are:

- Device drawing
- Device simulation
- Device/circuit mixed mode
- Visualization
- ✤ A text editor
- Spread sheet window
- ✤ X-Y graph plots.

### 2. RESULTS AND DISCUSSION

As we know that scaling the MOSFET below sub-20nm node will increase the DIBL value, sub-threshold slope, gate leakage, this is due to decreased gate coupling to the channel. These parameters are important for the performance of a device. Therefore it is necessary to reduce these above mentioned values. In this the doping concentration are varied so that improved performances are obtained. Firstly a device is designed which is explained below

In order to design a 10 nm Double gate MOSFET. It is important to make its geometry first in which various regions are well defined like source, drain, gate, body, Oxide. The doping is done in the source, drain and substrate regions. The materials of these regions are given in the table I below while the Table 2 shows various parameters and there values that we use in this device.

Region	Material
Source/drain	Al
Substrate	Silicon
Gate	n-poly Si
Oxide	SiO <sub>2</sub>

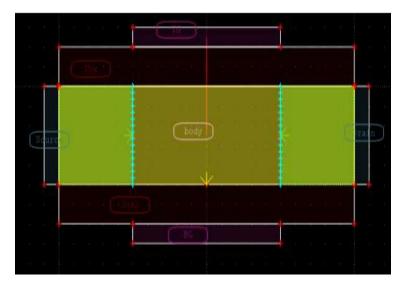
Table -1: Regions and materials used in MOSFET

Table -2: Parameters	and their v	zalues	of MOSFET
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Parameter	Length/T hickness	Mesh Size/Doping conc.	
Gate length	10 nm	Mesh size=.01	
Parameter	20nm	Mesh size=.005	
		1×10 <sup>15</sup> cm <sup>-3</sup> (acceptor)	
Source/drain	5nm	1×10 <sup>21</sup> cm <sup>-3</sup> (donor)	
Oxide(SiO <sub>2</sub> )	2nm	Mesh size=.01	

#### **Design and Simulations**

To design the 10 nm Double Gate MOSFET we make use of Visual TCAD tool which is device simulation tool. The geometry of DG MOSFET is shown below in Figure 5. The mesh file obtained is shown in Figure 6





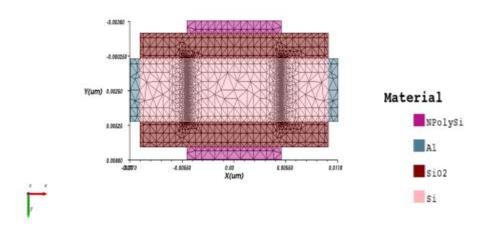


Figure 6: Material structure of 10 nm DG MOSFET

Once the simulations are done we obtain the  $I_{d}$ - $V_{g}$  plot shown in Figure 7. From  $I_{d}$  and  $v_{g}$  graph we can easily obtain threshold voltage ( $V_{th}$ ).it is the voltage at which channel is created. The drain voltage is taken as .05 V and the gate voltage is varied from 0v to 1v with start voltage equal to 0V and stop voltage equal to 1V with a voltage sweep of .01v. Figure 7 shows  $I_{d}$ - $v_{g}$  plot. It is clear from Figure 7 that the value of drain current Id increases after the  $V_{th}$ . These curves are obtained by using Genius simulator of Visual TCAD tool.

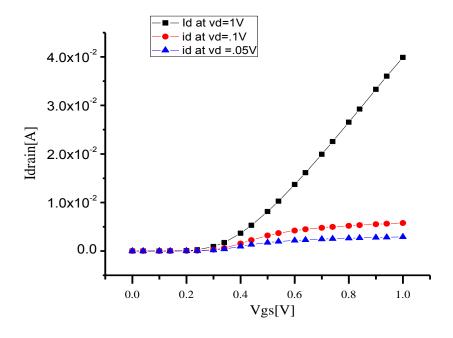


Figure 7: Id-Vgs plot of 10 nm DG MOSFET

In order to obtain  $I_{on}$  and  $I_{off}\,$  value, the transfer characteristics curve plotted between  $I_d$  and  $V_{gs}$  are shown Figure 8. From the very Graph we can obtain the value of leakage current and also we can obtain  $I_{on}$ - $I_{off}\,$  ratio .

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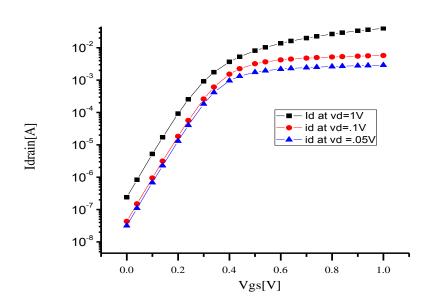


Figure 8: Transfer characteristics of MOSFET

Also we can obtain a plot between  $I_d$  and  $V_{ds}$ . In this the  $V_{gs}$  is kept constant where the  $V_{ds}$  is varied with start voltage equal to 0v and stop voltage equal 1v having voltage step of .1V. From the  $I_d$  vs  $V_d$  curve we can obtain value of transconductance .Figure 9 Shows Id- $V_{ds}$  plot of DG MOSFET.

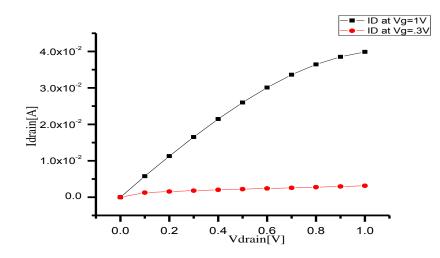


Figure 9: I<sub>d</sub> –V<sub>d</sub> curve of DG MOSFET.

The Simulation results of 10nm Double gate MOSFET are shown in Table 3.

Table 3: Simulation Results of MOSFET
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VDD	1v
Vth(V)	.22v
Leakage current(I <sub>off</sub> )	3.05×10 <sup>-8</sup> A
Drain current(I <sub>on</sub> )	3.02×10 <sup>-3</sup> A
I <sub>on</sub> /I <sub>off</sub>	9.9×10 <sup>4</sup>
DIBL	69.6 mV/V
Transconductance	2.7 ×10 <sup>-2</sup> Ω <sup>-1</sup>
Subthreshold Slope	81.6 mV/dec

L

#### **3. CONCLUSION**

10 nm Double gate mosfet is designed and analyzed on Visual Tcad tool in terms of *I-V* characteristics. From the simulation results of 10 nm Double gate it gives 0.22V threshold voltage at Vdd of 1V.Using an additional gate, the DIBL is reduced to 69.6mV/V. The leakage current of  $3.05 \times 10^{-8}$  A is observed due to which Ion/Ioff factor is improved to a greater extent. An optimum value of subthreshold slope is observed. These improved parameters suggested that the device designed at such dimension is very important for reducing short channel effects. A Visual TCAD is used which makes of drift diffusion model for transportation of carriers.

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